## **IN THE CLAIMS:**

## Amendments to the Claims

Please amend claims 1, 19 and 20 as shown below and please cancel claims 21-28, which stand withdrawn from consideration as being directed to non-elected inventions, without prejudice or disclaimer of the subject matter thereof and without prejudice to the right to file divisional applications directed thereto.

## **Listing of Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

- 1. (currently amended) A near-field optical probe, comprising:
- a substrate; and
- a metallic scatterer fabricated on said substrate in a contour of a circular cone or a polygonal pyramid having an axis vertical to a surface of the substrate;
  - wherein a localized plasmon is excited inside of said metallic scatter.
  - 2. (original) A near-field optical probe, comprising:
  - a substrate; and
- a metallic scatterer fabricated on said substrate in a contour of a planar ellipse having a major axis, a minor axis, and thickness, the major axis, the minor axis, and the thickness being equal to or less than a wavelength of light.
  - 3. (original) A near-field optical probe, comprising: a substrate; and

a metallic scatterer fabricated on said substrate in a contour of a triangle having a vertex with a radius of curvature and thickness, the radius of curvature and the thickness being equal to or less than a wavelength of light.

4. (original) A near-field optical probe, comprising:

a substrate; and

a metallic scatterer fabricated on said substrate in a contour of a triangle having a first vertex, second vertex, and a third vertex, the first vertex having a radius of curvature less than a radius of curvature of each of the second and third vertices.

- 5. (original) A near-field optical probe according to claim 3, wherein the triangle is connected to a film in a periphery of the triangle on the plane to dispose an opening in the connecting section, the opening having a radius of curvature greater than a radius of curvature of the vertex of the triangle.
- 6. (previously presented) A near-field optical probe, comprising a substrate on which a metallic film having a pointed tip end and a metallic film having an arbitrary contour are formed for generating a plasmon resonance, in which an interval between the pointed tip end metallic film and the arbitrarily contoured metallic film is equal to or less than 50 nm.
- 7. (previously presented) A near-field optical probe, comprising a substrate on which two metallic films each having a pointed tip end are formed for generating a plasmon resonance, in which an interval between the pointed tip ends is equal to or less than 50 nm.

- 8. (original) A near-field optical probe according to claim 1, further including in a periphery of said scatterer a metallic film, a dielectric film, or a semiconductor film having film thickness substantially equal to height of said scatterer.
- 9. A near-field optical probe according to claim 8, wherein: said film is a light shielding film; and said scatterer is apart from said peripheral film by a gap equal to or less than a wavelength of light.
- 10. (original) A near-field optical probe according to claim 1, further including a dip in the substrate surface with depth substantially equal to height of said scatterer, wherein said metallic scatterer is formed in said dip.
- 11. (original) A near-field optical probe according to claim 8, wherein a gap between said scatterer and said peripheral film or between said scatterer and said dip is filled with a light transmitting material.
- 12. (original) A near-field optical probe according to claim 1, wherein said substrate is a contour of a semi-sphere.
- 13. (original) A near-field optical probe according to claim 1, further including a light condensing element on said substrate.
- 14. (original) A near-field optical probe according to claim 13, wherein said light condensing element is a holographic lens.

- 15. (original) A near-field optical probe according to claim 1, wherein said metallic scatterer is formed on an edge surface of an optical resonator.
- 16. (original) A near-field optical probe according to claim 1, wherein said metallic scatterer is formed on a light emitting edge surface of a semiconductor laser.
  - 17. (original) A near-field optical probe, comprising:

a substrate; and

a metallic film having a pointed tip end in a contour of a planar ellipse or a triangle on a side surface or an inclined side surface of the substrate, said pointed tip end being brought into contact with a surface of a sample.

- 18. (original) A near-field optical probe according to claim 17, wherein said metallic film on the side surface of the substrate is coated with a transparent dielectric substance.
- 19. (currently amended) A near-field optical microscope including a near-field optical probe according to claim 18, wherein said near-field optical probe forms part of a near-field microscope.
- 20. (currently amended) An optical recording/reading device including a A near-field optical probe according to claim 17, wherein said near-field optical probe forms part of an optical recording/reading device.

Claims 21-28 (canceled)